

## Claims

[c1] What is claimed is:

1. A susceptor for semiconductor manufacturing equipment, comprising:  
a ceramic heater-block for installation within a processing chamber of semiconductor manufacturing equipment;  
an electroconductive component formed in the interior and/or on the surface of said ceramic heater-block;  
an electrode connected to said electroconductive component for supplying electricity thereto, said electrode being defined from where said electrode connects with said electroconductive component, to outside the processing chamber when said ceramic heater-block is installed therein.

[c2] 2. A susceptor as set forth in claim 1, further comprising a tubular piece formed encompassing said electrode.

[c3] 3. A susceptor as set forth in claim 2, further comprising a tubular piece formed encompassing said electrode; wherein an inert gas is introduced into the interior of said tubular piece.

- [c4] 4. A susceptor as set forth in claim 2, wherein the space within the interior of said tubular piece is isolated from the atmosphere inside the processing chamber when said ceramic heater-block is installed therein; and an inert gas is introduced into the interior of said tubular piece.
- [c5] 5. Semiconductor manufacturing equipment in which is installed a susceptor as set forth in claim 1.
- [c6] 6. Semiconductor manufacturing equipment in which is installed a susceptor as set forth in claim 2.
- [c7] 7. Semiconductor manufacturing equipment in which is installed a susceptor as set forth in claim 3.
- [c8] 8. Semiconductor manufacturing equipment in which is installed a susceptor as set forth in claim 4.